

# Diode laser-based beam sources and photodetectors

## 1 Laser diodes

### InP technology

- wavelength: 1250 nm ... 1750 nm
- optical power: 10 mW ... > 1 W
- Fabry-Perot, DFB, DBR, TPA, VCSEL

### **GaAs technology**

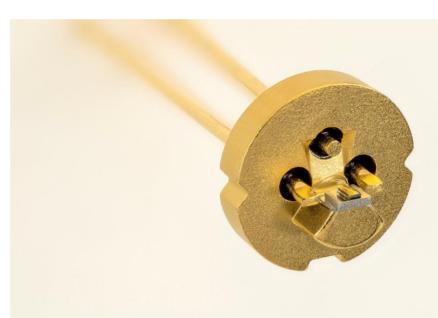
- wavelength: 630 nm ... 1180 nm
  optical power: 10 mW ... > 1 W
- Fabry-Perot, DFB, DBR, TPA, VCSEL

### GaN technology

- wavelength: ~ 400 nm
- optical power: a few 10 mW
- Fabry-Perot, DFB



GaN wafers with laser diodes



Laser diode mounted in TO housing

## 2 Photodetectors

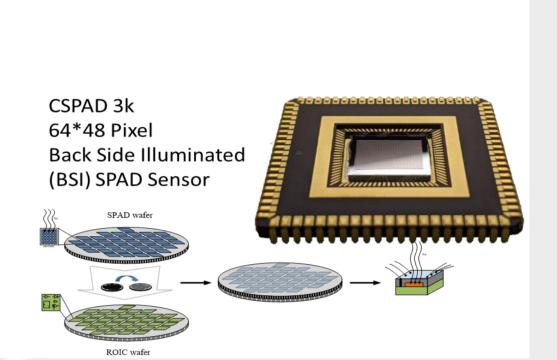
#### InP technology

- wavelength: 820 nm ... 2500 nm
- low-noise photodiodes with
- high quantum efficiency ( > 99%)
- Single photon detectors (SPAD) for 1064 nm to 1550 nm

### **CMOS** integrated SPADs (CSPAD)

- single photon detectors integrated in CMOS electronics (directly or through 3D integration)
- wavelengths: 300-1000 nm
- high photodetection efficiency > 60%
- low dark count rate < 0.1 counts/s</li>





# Wafer-level integrated solutions

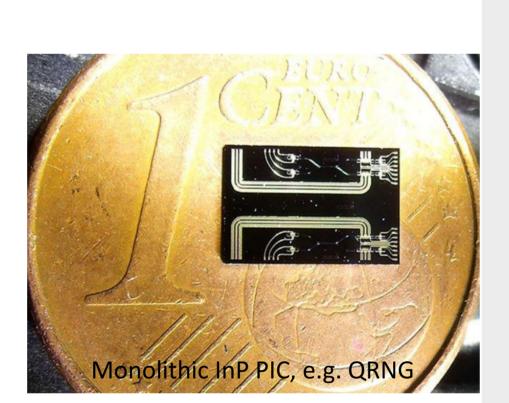
# Photonic integrated circuits (PIC) of active and passive components

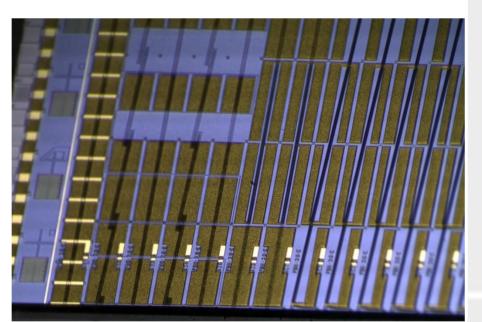
Monolithic integration of PICs

- on InP and GaAs:
- laser
- Mach-Zehnder modulator
- Photodiode

### **Hybrid integration**

- thermo-compression bonding with nanoporous gold and gold-gold
- perpendicular-assisted self-alignment with AuSn
- indium bumps with large differences in the thermal expansion





ECDL monolithically integrated in GaAs

## Discrete heterointegrated solutions

# Photonic integrated circuits of passive waveguide networks

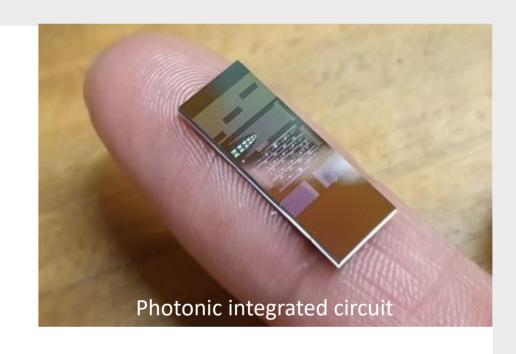
- SiN-on-insulator
- AIN, AI<sub>2</sub>O<sub>3</sub> (previously only 1550 nm)
- LiNbO<sub>3</sub>-on-insulator
- integrated resonators and gratings in glass platforms for narrowband lasers (ECDL)

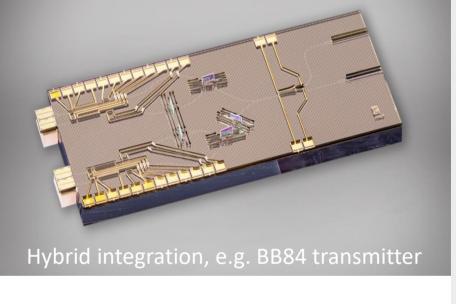
### **Hybrid integration**

 sub-assemblies of active components such as lasers and photodiodes with passive photonic integrated circuits

### **Micro-assembly**

- ultra-precise (< 100 nm) micromounting</li>
- adhesive bonding, robust & compact
- integrated optical build-up platforms made of glass with hermetic encapsulation







## 5 Outlook

Task: Development of scalable manufacturing technologies for complex beam sources

### Wafer-level hetero-integration,

- Co-integration with Light Control Units & Physics Package
- Flip-chip assembly, transfer printing, wafer-to-wafer bonding

### Discrete heterointegration

for solutions that cannot (yet) be integrated at wafer level

